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We are pleased to inform you that your submitted abstract is accepted by Technical Program Committee for presentation at ICAE 2017. You can also check the result of review at the website (<http://www.icae.kr>) by logging in with your ID and Password.

Abstract No.	A20170630-3399
Abstract Title	Metal Organic Chemical Vapor Deposition (MOCVD) Growth of High Quality GaN Layer on 4H-SiC Substrate for Ultraviolet Avalanche Photodiode Applications.
Symposium	[Symposium 11] Thin Film Processing : Characterization, Growth, and Devices
Presentation Preference	Poster
Corresponding Author	Dr. Joo Jin
Presenting Author	Mr. Jiwon Jeong
Author(s)	Mr. Jiwon Jeong, Mr. Joocheol Jeong, Dr. Junghwan Son, Dr. Joo Jin
Result of Review	Acceptance

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KIEEME (The Korean Institute of Electrical and Electronic Material Engineers)

Rm 807, The Korea Science & Technology Center, 22, 7gil, Teheran-ro Gangnam-gu, Seoul 06130, Korea

Tel: +82-2-565-3571 E-mail: secretary@icae.kr